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PTO/SB/08b (08-03) (AW 10/2003)

Approved for use through 6/30/2008. OMB 0651-0031

U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

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Substitute for Form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Use as many sheets as necessary)</i>	Complete if Known	
	Application Number	To Be Assigned
	Filing Date	Herewith
	First Named Inventor	Ming Li et al.
	Art Unit	To Be Assigned
	Examiner Name	To Be Assigned
SHEET 1 of 1		Attorney Docket No. MATG-401US

NON-PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (In CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
AE	1.	MING LI ET AL., Nanostructuring in submicron-level waveguides with femtosecond laser pulses, Optics Communications, Elsevier Science B.V., September 2002, (5 pgs.)	<input type="checkbox"/>
AE	2.	MING LI ET AL., Ultra-precision machining using fs fast Laser: An application for Photonic Crystal fabrication, Fs Ultra-maching Workshop, March 5, 2003, (53 pgs.)	<input type="checkbox"/>
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Examiner Signature	M. Alexandra Elve		Date Considered 3/4/06

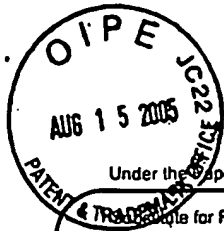
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¹Applicant's unique citation designation number (optional).

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Form 1449B/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	10/790,401
Filing Date	March 1, 2004
First Named Inventor	Ming Li et al.
Art Unit	2812
Examiner Name	Steven J. Fulk
Attorney Docket No.	MATG-401US

SHEET 1 of 1

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
AC	1.	LI M. et al.: "Femtosecond Laser Micromachining of Si-on-SiO ₂ for Photonic Band Gap Crystal Fabrication"; Japanese Journal of Applied Physics; Publication Office Japanese Journal of applied Physics; Tokyo, JP, vol. 40, no. 5A, Part 1, May 2001 (2001-05), pages 3476-3477; XP001078634; ISSN: 0021-4922	<input type="checkbox"/>
	2.	KORTE F. et al.: "Toward Nanostructuring with Femtosecond Laser Pulses"; Nanotechnology, 19-21 May 2003, Maspalomas, Gran Canaria, Spain, Proceedings of the SPIE, vol. 5118, 2003, pages 93-100, XP002326971; USA, ISSN: 0277-786X	<input type="checkbox"/>
	3.	WATANABE, OSAMU et al.: "Nanofabrication induced by near-field exposure from a nanosecond laser pulse"; Applied Physics Letters, American Institute of Physics, New York, US, vol. 79, no. 9, August 27, 2001 (2001-08-27), pages 1366-1368, XP012030175; ISSN: 0003-6951	<input type="checkbox"/>
	4.	ENDERS, O. et al.: "Lorentz-Force-Induced Excitation of Cantilevers for Oscillation-Mode Scanning Probe Microscopy"; German-Chinese Workshop on Fundamentals and Applications of Nanoscience: Building Blocks, Modelling and Structuring, 1-4, July 2002, Karlsruhe, Germany, Surface and Interface Analysis Wiley, vol. 36, no. 2, February 2004 (2004-02), pages 119-123, XP009047231; UK, ISSN: 0142-2421, section "Microstructuring the Cantilever Chip", page 120	<input type="checkbox"/>
AC	5.	OSTLENDER A. et al.: "Metrology for Laser-Structured Microdevices by CCD-Camera-Based Vision Systems"; Moems and Miniaturized Systems, 18-20, Sept. 2000, Santa Clara, CA, USA, Proceedings of the SPIE, vol. 4178, 2000, pages 197-206, XP002326972, USA, ISSN: 0277-786X, page 199, "3. Metrology for 3D Measurements", page 203, "7. Tests"	<input type="checkbox"/>
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			<input type="checkbox"/>

Examiner
Signature

M. Alexandra Elie

Date
Considered

3/4/06

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